



ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18
Stylesheet Version v18.0

Title of Invention	MODIFIED TRANSFER FUNCTION DEPOSITION BAFFLES AND HIGH DENSITY PLASMA IGNITION THEREWITH IN SEMICONDUCTOR PROCESSING										
Application Number:		10/080496									
Confirmation Number:		8492									
First Named Applicant:		Jozef Brcka									
Attorney Docket Number:		TAZ213									
Art Unit:		1763									
Examiner:		Luz L.									
Search string:		(6287435).pn.									
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<p><u>Certification:</u> This Information Disclosure Statement was submitted under the following conditions, which satisfies the requirement under 37 CFR 1.97(e). The filer certified:</p> <p>That each item of information contained in the information disclosure statement was first cited in any communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of the information disclosure statement.</p> <p>US Patent Documents</p> <p>Note: Applicant is not required to submit a paper copy of cited US Patent Documents</p>											
Init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass				
	1	6287435	2001-09-11	Drewery et al.							
<p>Signature</p> <table border="1"><tr><td>Examiner Name</td><td>Date</td></tr><tr><td></td><td>12/23/03</td></tr></table>								Examiner Name	Date		12/23/03
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